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ATTENTION: BOX AFTER FINAL  
RESPONSE UNDER 37 C.F.R. § 1.116  
EXPEDITED PROCEDURE REQUESTED  
EXAMINING GROUP 1762

PATENT  
Customer No. 22,852  
Attorney Docket No. 08038.0019-00000

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: )  
)  
H. AMANO ) Group Art Unit: 1762  
)  
Application No.: 09/657,050 ) Examiner: M. L. Padgett  
)  
Filed: September 7, 2000 )  
)  
For: Device and Method for Plasma )  
Processing )

Assistant Commissioner for Patents  
Washington, DC 20231

Sir:

AMENDMENT AFTER FINAL

In reply to the Final Office Action of November 12, 2002, and pursuant to  
37 C.F.R. § 1.116, Applicant requests that this application be amended as follows:

IN THE CLAIMS:

Please cancel claim 9.

Please amend claims 1 and 8 as follows:

1. (Twice Amended) A plasma processing apparatus comprising:  
a plurality of plasma processing units, each having a vacuum processing  
chamber including a mounting stage for mounting a substrate with a fixed reference  
point and a wave guide bent at an angle for introducing high frequency waves into said

FINNEGAN  
HENDERSON  
FARABOW  
GARRETT &  
DUNNER LLP

1300 I Street, NW  
Washington, DC 20005  
202.408.4000  
Fax 202.408.4400  
www.finnegan.com